## **CYBER** OPTICS

## CyberOptics to Share Technical Presentation about Delivering Yield Improvements at SPIE PhotoMask Japan

**Minneapolis, Minnesota** — March 22, 2022 — <u>CyberOptics® Corporation</u> (NASDAQ: CYBE), a leading global developer and manufacturer of high-precision 3D sensing technology solutions, will present at the virtual PhotoMask Japan, the 28th symposium on photomask and next-generation lithography mask technology on April 27, 2022 at 15:20 JST. CyberOptics is a gold sponsor of the online symposium that will be held from April 26-28, 2022.

Mr. Yukinobu Hayashi, CyberOptics' Applications Engineer and Account Manager based in Japan, will share the technical presentation "Improving Yields and Tool Uptime with Wireless Measurement Sensors in Semiconductor Environments."

Stringent manufacturing requirements and a focus on maximizing yields and tool uptime drives a need for best-in-class practices for a contamination-free process environment. Quickly identifying when and where airborne particles originate as well as the source of the contamination is vital.



To address this critical need, an In-Line Particle Sensor<sup>™</sup> (IPS<sup>™</sup>) can be used for effective semiconductor tool set-up and process diagnostics. The IPS is an extension of the industry-leading WaferSense<sup>®</sup> and ReticleSense<sup>®</sup> Airborne Particle Sensors (APS<sup>™</sup> and APSRQ<sup>™</sup>) that are documented by fabs as the Best-Known Method (BKM).

The IPS and accompanying CyberSpectrum<sup>™</sup> software can identify, measure, monitor and troubleshoot particles down to 0.1µm in gas and vacuum lines 24/7/365 in semiconductor process equipment. Contamination sources can be identified quickly and the effects of cleaning, adjustments and repairs can be seen in real-time. It is particularly relevant to EUVL tools where it can be installed at the vacuum line in



between the EUV process chamber and the vacuum pump, saving significant time compared to current methods to check for particles. The IPS is always on and collecting particle data, which is especially critical during chamber purging.

ReticleSense<sup>®</sup> APSRQ and Auto Multi Sensors<sup>™</sup> (AMSR<sup>™</sup>) will also be highlighted. The all-in-one AMSR can

measure and monitor leveling, vibration and relative humidity (RH) in reticle environments. Overall, by adopting the IPS, APSRQ and AMSR devices, significant reductions in time and expense can be recognized, while improving yields and tool uptime.

For more information, visit <u>www.cyberoptics.com</u>.

## About CyberOptics

CyberOptics Corporation (www.cyberoptics.com) is a leading global developer and manufacturer of highprecision 3D sensing technology solutions. CyberOptics' sensors are used for inspection and metrology in the SMT and semiconductor markets to significantly improve yields and productivity. By leveraging its leading edge technologies, the Company has strategically established itself as a global leader in high precision 3D sensors, allowing CyberOptics to further increase its penetration of key vertical markets. Headquartered in Minneapolis, Minnesota, CyberOptics conducts worldwide operations through its facilities in North America, Asia and Europe.

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